

## REFERENCES

- Abdelaziz M.E., Zakhary S.G., and Ragheb M.S. 2000. Rev. Sci. Instrum. **71** 1137.
- Alton G.D. 1981. Nucl. Instr. and Meth in Phys. Res. **189** 15.
- Azam S., Xu S., Lee S., Ahn J., Tien O.J., Chen X.F. and Lim L.C. 1998. Sing. J. Phys. **14(1)** 57.
- Becker, R. and Herrmannsfeldt, W.B. 1992. Rev. Sci. Instrum. **63 (4)** 2756.
- Birdsall C.K. and Langdon A.B. 1991. *Plasma Physics via Computer Simulation*. Bristol: Adam Hilger.
- Boonyawan D., Suanpoot P., and Vilaithong T. 1999. Surf. Coat. Technol. **112** 314.
- Bruenger W.H., Torkler M. Leung K.N., Lee Y. Williams M.D. Loeschner H., Stengl G., Fallmann W., Paschke F., Stangl G., Rangelow I.W. and Hudek P. 1999. Microelectronic Engineering **46** 477.
- Cavennago, M. and Bisoffi, G. 1991. Rev. Sci. Instrum. **62(8)** 1970.
- Chapman B. 1980. *Glow Discharge Processes*. New York: John Wiley & Son.
- Chen F.F. 1984. *Introductions to Plasma Physics and Controlled Fusion*. New York: Plenum.
- Engemann J. 2001. Personal communications.
- Gamo, K. 1997. Nucl. Instr. and Meth. **B121**, 464.
- Godfrey L., Hoyes G.G. and Pairsuwan W. 1990. Nucl. Instrum. and Meth. B **51** 294.
- Gudmundsson J.T., and Lieberman M.A. 1997. Plasma Sources Sci. Technol. **6** 540.
- Gudmundsson J.T. 2001. Plasma Sources Sci. Technol. **10** 76.
- Hiden : Electrostatic Probe Analyzer manual 1996.
- Holmes, A.J. 1979. Physical Review A. **19 (1)** 389.
- Ishikawa J. 1998. Rev. Sci. Instrum. **69** 863.
- Itakura, T., Horiuchi, K. and Yamamoto, S. 1985. Microelectronic Engineering **3** 153.

- Junphong P. 1999. *Design and Construction of a Quadrupole Magnet for 3 MeV Electron Beam Focusing*. M.S. Thesis, Chiang Mai University.
- Kasahara, H., Sawaragi, H., Aihara, R., Gamo, K., Namba, S. and Sheare, M.H. 1988. J. Vac. Sci. Technol. B 6 (3) 974-976.
- Kalbitzer, S. 1996. Nucl. Instr. and Meth. B113, 154.
- Keller J.H. 1996. Plasma Sources Sci. Technol. 5 166.
- KOBRA3-INP Manual, Spedtke P. INP, Germany 1999.
- Kolobov V.I., and Economou D.J. 1997. Plasma Sources Sci. Technol. 6 R1.
- Kuo T., Yuan D., Jayamanna K., McDonald M., Baartman R., Mackenzie G., Bricault P., Dombsky M., Schmor P., Dutto G., Lee Y., Leung K.N., Williams D., and Gough R. 1998. IEEE Trans. on Plasma Science 2675.
- Lee Y., Gough R.A., Kunkel W.B., Leung K.N., Perkins L.T., Pickard D.S., Sun L., Vujic J., Williams M.D., Wutte D., Mondelli A.A. and Stengl G. 1997. Nucl. Instr. and Meth in Phys. Res. A 385 204.
- Lee Y., Gough R.A., Kunkel W.B., Leung K.N., Perkins L.T., Pickard D.S., Sun L., Vujic J., Williams M.D. and Wutte D. 1997. Rev. Sci. Instrum. 68 1398.
- Lee Y., Gough R.A., Leung K.N., Perkins L.T., Pickard D.S., Vujic J., Wu L.K., Olivo M. and Einenkel H. 1998. Rev. Sci. Instrum. 69(2) 1023.
- Lee Y., Gough R.A., King T.J., Ji Q., Leung K.N., McGill R.A., Ngo V.V., Williams M.D., and Zahir N. 1999. Microelectronic Engineering 46 469.
- Leung K.N., Samec T.K. and Lamm A. 1975. Phys. Letters 51A(8) 490.
- Leung K.N., Collier R.D., Marshall L.B., Gallaher T.N., Ingham W.H., Kribel R.E. and Taylor G.R. 1978. Rev. Sci. Instrum. 49(3) 321.
- Leung K.N. and Keller R. 1990. Rev. Sci. Instrum. 61 333.
- Leung, K.N., DeVries, G.J., DiVergilio, W.F., Hamm, R.W. Hauck, C.A. Kunkle, W.B., McDonald, D.S. and Williams, M.D. 1991. Rev. Sci. Instrum. 62 (1) 100.
- Leung, K.N., Bachman, D.A., Herz, P.R. and McDonald, D.S. 1993. Nucl. Instr. And Meth. B74 291.

- Lichtenberg T. 1985. *Plasma Diagnostics*. New York: Academic Press.
- Lide D.R. 1994. *Handbook of Chemistry and Physics*. New York: CRC Press.
- Lieberman M.A. and Lichtenberg A.J. 1994. *Principles of Plasma Discharges and Material Processing*. New York: John Wiley & Son.
- Limpaecher R. and MacKenzie K.R. 1973. Rev. Sci. Instrum. 44 726.
- Lister G.G., and Cox M. 1991. Plasma Sources Sci. Technol. 1 67.
- MAGNUS, A Three-Dimensional Non-Linear Magnetostatic, Computer Program FL: Ferrari Associates, Inc. 1987.
- Menard J. and Intrator T. 1996. Plasma Sources Sci. Technol. 5 363.
- Melngailis, J. 1993. Nucl. Instr. and Meth. B80/81, 1271.
- Nakamura, K., Kuwashita, Y. and Sugai, H. 1995. Jpn. J. Appl. Phys. 34 1686.
- NIST Atomic Spectra Database Line Data. 2001. (<http://physics.nist.gov>).
- Ocean Optics S-2000 :PC base spectrometer user manual. 2000.
- Orloff, J. 1996. *Handbook of Charge Particle Optics*. New York: CRC Press, Inc. 429.
- Orloff, J. 1993. Rev. Sci. Instrum. 64 (5) 1105.
- Ovsyannikova, L.P. and Fishkova, T.Ya. 1996. Tech. Phys. Lett. 22(8) 660.
- Piejak R.B., Godyak V.A., and Alexandrovich B.M. 1992. Plasma Sources Sci. Technol. 1 179.
- Perkins L.T. 1997. *A Compact Ion Source for Intense Neutron Generation* PhD. Thsis University of California, Berkeley.
- Reijonen J., Heikkinen P., Liukkonen E. and Arje J. 1998. Rev. Sci Instrum. 69 1138.
- Rhodes M.W., Wanwilairat S., Vilaithong T. and Hoffmann W. 2000. Rev. Sci. Instrum. 71(5) 2053.
- Roth J.R. 1995. *Industrial Plasma Engineering*. London: IOP Publishing Ltd 404.
- Sarstedt M., Lee Y., Leung K.N., Perkins L.T., Pickard D.S., Weber M., and Williams M.D. 1996. Rev. Sci. Instrum. 67 1249.
- Scipioni L., Stewart D., Ferranti D., and Saxonis A. 2000. J. Vac. Sci. Technol. B18(6) 3194.

- Shirakawa T., Toyoda H. and Sugai H. Jpn. 1990. *J. Appl. Phys.* **29(6)** L1015.
- Shubaly M.R. 1987. *Nucl. Instr. and Meth in Phys. Res. B* **26** 195.
- Strehl P. 1995. *Handbook of Ion Sources*. New York: CRC Press 437.
- Suanpoot P., Boonyawan D., Rhodes M. and Vilaithong T. 1998. *J. Plasma Fusion Res. SERIES*, Vol. 1 526.
- Suzuki K., Nakamura K., Ohkubo H., and Sugai H. 1998. *Plasma Sources Sci. Technol.* **7** 13.
- Valyi, L. 1997. *Atom and Ion Sources*. London: John Wiley & Sons 154.
- Vasile, M., Biddick, C. and Schwalm, S. 1994. *J. Vac. Sci. Technol. B* **12(4)** 2388.
- Verboncoeur J.P., Langdon A.B. and Gladd N.T. 1995. *Comp. Phys. Comm.* **87** 199.
- Wiedemann H. 1997 *Particle Accelerator Physics I*. Berlin: Springer-Verlag 152.
- Wiedemann H. 2001. Personal communications.
- Wille K. 2000. *Physics of Particles Accelerators: an Introduction*. Oxford University Press
- Wolf B. 1995. *Handbook of Ion Source*. New York: CRC Press, Inc. 239.
- Wutte D., Freedman S., Gough R., Lee Y., Leitner M., Leung K.N., Lyneis C., Pickard D.S., Williams M.D. and Xie Z.Q. 1998. *Nucl. Instr. and Meth in Phys. Res. B* **142** 409.
- Yamauchi, K., Takahashi, K. and Yabe, E. 1993. *Rev. Sci. Instrum.* **64 (9)** 2434.
- Yang J.G., Yoon N.S., Kim B.C., Choi J.H., Lee G.S., and Hwang S.M. 1999. *IEEE Trans. on Plasma Science* **27(3)** 676.
- You K.I., and Yoon N.S. 1999. *Physical Rev. E* **59(6)** 7074.
- Zakhary G. 1995. *Rev. Sci. Instrum.* **66** 5419.
- Zhang H. 1999. *Ion Sources*. Berlin: Springer 206.
- Zorat R., Goss J., Boilson D., and Vender D. 2000. *Plasma Sources Sci. Technol.* **9** 161.